



PATENT

Atty. Dkt. No. APPM/005191.C1/ISM/CORE/MCVD/PJS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Lawrence C. Lei

Serial No.: 10/792,323

Confirmation No.: 4370

Filed: March 3, 2004

For: Apparatus and Method for
Vaporizing Solid Precursor
for CVD or Atomic Layer
Deposition

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Group Art Unit: 3742

Examiner: Sang Yeop Paik

CERTIFICATE OF MAILING
37 CFR 1.8

RESPONSE TO OFFICE ACTION DATED JUNE 23, 2005

In response to the Office Action dated June 23, 2005, having a shortened statutory period for response set to expire on September 23, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/005191.C1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Specification begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 6 of this paper.